

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/649,695	KOKUBUN ET AL.	
Examiner		Art Unit		Page 1 of 1
John Hoffmann		1731		

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,888,994 B2	05-2005	Baumberg et al.	385/129
*	B	US-6,413,583 B1	07-2002	Moghadam et al.	427/249.15
*	C	US-6,106,678 A	08-2000	Shufflebotham et al.	204/192.32
*	D	US-6,690,871 B2	02-2004	Lee et al.	385/129
*	E	US-5,198,008 A	03-1993	Thomas, Michael E.	65/386
*	F	US-4,998,793	03-1991	Henry et al.	385/1
*	G	US-4,978,189	12-1990	Blonder et al.	385/35
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	LOBODA, M.J. et al, "Using Trimethylsilane to Improve Safety, Throughput and Versatilitiy in PECVD Processes", Proceedings of the symposium on Silicocn nitride and silicocn dioxide thing insulating films, (1997) pp. 443-453.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.